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10/597,996	08/15/2006	Radu Catalin Surdeanu	NL04 0166 US1	8935
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NXP, B.V. NXP INTELLECTUAL PROPERTY & LICENSING M/S41-SJ 1109 MCKAY DRIVE SAN JOSE, CA 95131			EXAMINER TRAN, TRANG Q	
			ART UNIT 2811	PAPER NUMBER
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**Please find below and/or attached an Office communication concerning this application or proceeding.**

The time period for reply, if any, is set in the attached communication.

Notice of the Office communication was sent electronically on above-indicated "Notification Date" to the following e-mail address(es):

ip.department.us@nxp.com

**Office Action Summary****Application No.**

10/597,996

**Applicant(s)**

SURDEANU ET AL.

**Examiner**

TRANG Q. TRAN

**Art Unit**

2811

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --  
**Period for Reply**

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

**Status**

- 1) ☒ Responsive to communication(s) filed on 30 March 2010.  
2a) ☒ This action is **FINAL**. 2b) ☐ This action is non-final.  
3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

**Disposition of Claims**

- 4) ☒ Claim(s) 1-3 and 5-21 is/are pending in the application.  
4a) Of the above claim(s) \_\_\_\_\_ is/are withdrawn from consideration.  
5) ☐ Claim(s) \_\_\_\_\_ is/are allowed.  
6) ☒ Claim(s) 1-3, 5-21 is/are rejected.  
7) ☐ Claim(s) \_\_\_\_\_ is/are objected to.  
8) ☐ Claim(s) \_\_\_\_\_ are subject to restriction and/or election requirement.

**Application Papers**

- 9) ☐ The specification is objected to by the Examiner.  
10) ☒ The drawing(s) filed on 15 August 2006 is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.  
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).  
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).  
11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

**Priority under 35 U.S.C. § 119**

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).  
a) ☒ All b) ☐ Some \* c) ☐ None of:  
1. ☒ Certified copies of the priority documents have been received.  
2. ☐ Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.  
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

\* See the attached detailed Office action for a list of the certified copies not received.

**Attachment(s)**

- 1) ☐ Notice of References Cited (PTO-892)  
2) ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)  
3) ☐ Information Disclosure Statement(s) (PTO/SI/08)  
Paper No(s)/Mail Date \_\_\_\_\_  
4) ☐ Interview Summary (PTO-413)  
Paper No(s)/Mail Date \_\_\_\_\_  
5) ☐ Notice of Informal Patent Application  
6) ☐ Other: \_\_\_\_\_

## **DETAILED ACTION**

### ***Response to Arguments***

Applicant's response filed on March 30, 2010 is acknowledged and is answered as follows.

Applicant's arguments, see pgs. 6-8, with respect to the rejection of claim 1 that "the Office Action fails to describe what the achieved device properties are and how combining the L-shape of the side wall of Krivokapic into Pellerin would achieve such device properties" have been fully considered but they are not persuasive in view of the following reasons.

The examiner recognizes that obviousness may be established by combining or modifying the teachings of the prior art to produce the claimed invention where there is some teaching, suggestion, or motivation to do so found either in the references themselves or in the knowledge generally available to one of ordinary skill in the art. See *In re Fine*, 837 F.2d 1071, 5 USPQ2d 1596 (Fed. Cir. 1988), *In re Jones*, 958 F.2d 347, 21 USPQ2d 1941 (Fed. Cir. 1992), and *KSR International Co. v. Teleflex, Inc.*, 550 U.S. 398, 82 USPQ2d 1385 (2007). In this case, the shape of the side wall spacer was a matter of choice to isolate active element.

According to M.P.E.P. § 2144.04(IV)(B), the court held that the configuration of the claimed disposable plastic nursing container was a matter of choice which a person of ordinary skill in the art would have found obvious absent persuasive evidence that the particular configuration of the claimed container was significant. See *In re Dailey*, 357 F.2d 669, 149 USPQ 47 (CCPA 1966).

In Dailey, the court stated that “[a]ppellants have presented no argument which convinces us that the particular configuration of their container is significant or is anything more than one of numerous configurations a person of ordinary skill in the art would find obvious” (357 F.2d at 672-73, 149 USPQ at 50).

In view of the foregoing reasons, the Examiner believes that all Applicant's arguments and remarks are addressed. The Examiner has determined that the previous Office Action is still proper based on the above responses. Therefore, the rejections are sustained and maintained.

### ***Claim Rejections - 35 USC § 103***

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

Claims 1-3, and 5-12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Pellerin (WO 02/075781 A2) in view of Krivokapic (US 6,888,198).

**Re. claim 1**, Figs. 2A-2D of Pellerin disclose a semiconductor device comprising a silicon-containing semiconductor body (30) with a surface, which semiconductor body (30) is provided, near the surface thereof, with a transistor comprising: a gate (46) situated at the surface and having a side wall spacer (52) on either side of the gate (as seen in Fig. 2D), and further comprising, on either side of the gate (46), a diffusion

region (44) formed in the semiconductor body (30), at least one diffusion region (44+extension implant region 46) being provided at the surface of the semiconductor body (30) with a silicide region (50), characterized in that the silicide region (50) extends along the surface of the semiconductor body (30) and continues for more than 10 nm (Pg. 6, lines 18-19 of Pellerin discloses side wall spacer 52 having thickness (53) from 20 nm to 100 nm which overlaps with the silicide region; therefore Pellerin discloses the silicide region (50) continues for more than 10 nm under the sidewall spacer) under the side wall spacer (52).

Pellerin discloses the semiconductor device as claimed in claim 1, characterized in that the side wall spacer (52) has a shaped (as seen Fig. 2) and comprises a first portion, which borders on the gate and extends substantially perpendicularly with respect to the surface of the semiconductor body, and a second portion which extends along the surface of the semiconductor body (as seen in Fig. 2D).

However, Pellerin does not disclose the following limitation whereas Fig. 1 of Krivokapic teaches it is known in the art to provide a side wall spacer (48 or 60) is L-shaped.

It would have been obvious to one of ordinary skill in the art at the time of the invention was made to provide the L-shape of the side wall of Krivokapic in Pellerin, order to isolate the active element.

Furthermore, the shape of the side wall spacer was a matter of choice which a person of ordinary skill in the art would have found obvious absent persuasive evidence that the particular configuration of the side wall spacer was significant. See *In re Dailey*,

357 F.2d 669, 149 USPQ 47 (CCPA 1966).

**Re. claim 2**, Pellerin and Krivokapic disclose the semiconductor device as claimed in claim 1, Pellerin further discloses characterized in that the silicide region (50) contains a metal (see pg. 5, lines 39-40) which, in the silicide region formed, has a higher diffusion rate than silicon (Pellerin teaches the silicide region has the same material as claimed invention; therefore it has higher diffusion rate than silicon, see claim 3 below for claimed material).

**Re. claim 3**, Pellerin and Krivokapic disclose the semiconductor device as claimed in claim 2, Pellerin further discloses characterized in that the metal is selected from the group comprising nickel (Ni), platinum (Pt) (see pg. 5, lines 39-40).

**Re. claim 5**, Pellerin and Krivokapic disclose teaches semiconductor device as claimed in claim 1, however Pellerin and Krivokapic may not explicitly teach the second portion of the L-shaped side wall spacer has a thickness, measured in a direction perpendicular to the surface of the semiconductor body, of maximally 40 nm.

According to MPEP § 2144.04(IV)(A): In *Gardner v. TEC Systems, Inc.*, 725 F.2d 1338, 220 USPQ 777 (Fed. Cir. 1984), cert. denied, 469 U.S. 830, 225 USPQ 232 (1984), the Federal Circuit held that, where the only difference between the prior art and the claims was a recitation of relative dimensions of the claimed device and a device

having the claimed relative dimensions would not perform differently than the prior art device, the claimed device was not patentably distinct from the prior art device.

It would have been obvious to one having ordinary skill in the art at the time the invention was made to provide certain measurement, since it has been held that discovering the optimum or workable ranges involves only routine skill in the art. *In re Aller*, 105 USPQ 233; *In re Boesch*, 617 F.2d 272, 205 USPQ 215 (CCPA 1980); *In re Huang*, 100 F.3d 135, 40 USPQ2d 1685, 1688 (Fed. Cir. 1996).

**Re. claim 6**, Pellerin and Krivokapic disclose the semiconductor device as claimed in claim 1, however Pellerin and Krivokapic may not explicitly teach whereas Fig. 1 of Krivokapic teaches it known in the art to provide an insulating layer (14) extends in the semiconductor body (12) in a direction parallel to the surface of the semiconductor body (12, as seen in fig. 1).

It would have been obvious to one having ordinary skill in the art at the time the invention was made to provide the insulating layer of Krivokapic in Pellerin, in order to define the active regions (Col. 1 lines 66-67, and Col. 2, line 1).

**Re. claims 7-8**, Pellerin and Krivokapic disclose the semiconductor device as claimed in claim 1, however Pellerin and Krivokapic may not explicitly teach whereas Fig. 1 and Col 2, lines 14-15 of Krivokapic discloses characterized in that the semiconductor body comprises a germanium component or strained-silicon layer (as seen in Col 2, lines 14-15).

It would have been obvious to one having ordinary skill in the art at the time the invention was made to provide the semiconductor body comprises a germanium component or strained-silicon layer of Krivokapic in Pellerin, in order to improve the performance of the device.

**Re. claim 9**, Pellerin and Krivokapic disclose the semiconductor device as claimed in claim 1, Pellerin further discloses characterized in that the at least one diffusion region (44+extension implant region 46) comprises the silicide region (50) as seen in Figs. 2A-2D.

**Re. claim 11**, Pellerin and Krivokapic disclose the semiconductor device as claimed in claim 1, Pellerin further discloses characterized in that the silicide region (50) is completely below the side wall spacer (52).

**Claims 10 and 12** are rejected under 35 U.S.C. 103(a) as being unpatentable over Pellerin in view of Yang et al. (US 2003/0162359).

**Re. claim 10**, Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses characterized in that the at least one diffusion region comprises a diffusion region extension (extension implant region 46),

However Pellerin and Krivokapic disclose may not explicitly teach whereas Fig. 2 of Yang discloses the silicide region (260) comprising a silicide region extension (262),



the silicide region extension falling completely within the diffusion region extension (242).

It would have been obvious to one having ordinary skill in the art at the time the invention was made to provide the silicide region extension of Yang in Pellerin; in order to decrease contact resistance.

**Re. claim 12,** Pellerin and Krivokapic disclose the semiconductor device as claimed in claim 2, however Pellerin and Krivokapic disclose may not explicitly teach whereas Fig. 2 and ¶28 of Yang discloses characterized in that the silicide layer (260) comprising metal which is palladium (Pd).

It would have been obvious to one having ordinary skill in the art at the time the invention was made to provide the silicide layer having claimed material, in order for suitable material use.

It would have been obvious to one of ordinary skill in the art at the time the invention was made to provide claimed material for silicide layer, since it have been held to be within the general skill of a worker in the art to select a know material on the basis of its suitability for the intended use as a matter of obvious design choice. In re Leshin, 125 USPQ 416

Claims 13-21 are rejected under 35 U.S.C. 103(a) as being unpatentable over Pellerin (WO 02/075781 A2) in view of Krivokapic (US 6,888,198).

**Re. claim 1**, Figs. 2A-2D of Pellerin disclose a semiconductor device comprising a silicon-containing semiconductor body (30) with a surface, which semiconductor body (30) is provided, near the surface thereof, with a transistor comprising: a gate (46) situated at the surface and having a side wall spacer (40/52) on either side of the gate (as seen in Fig. 2D), and further comprising, on either side of the gate (46/50), a diffusion region (44) formed in the semiconductor body (30), at least one diffusion region (44+extension implant region 46) being provided at the surface of the semiconductor body (30) with a silicide region (50), characterized in that the silicide region (50) extends along the surface of the semiconductor body (30) and continues under the side wall spacer

Pellerin does not disclose the silicide region continues for more than 10 nm under the side wall spacer.

It would have been obvious to one having ordinary skill in the art at the time of the invention was made to include the silicide region continues for more than 10 nm under the side wall spacer, in order to optimize the performance of the device.

Furthermore, it has been held that where then general conditions of a claim are disclosed in the prior art, discovering the optimum or workable ranges involves only routine skill in the art. *In re Aller*, 105 USPQ 233.

Furthermore, it has been held in that the applicant must show that a particular range is critical, generally by showing that the claimed range achieves unexpected results relative to the prior art range. *In re Woodruff*, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990). Note that the law is replete with cases in which when the

mere difference between the claimed invention and the prior art is some dimensional limitation or other variable within the claims, patentability cannot be found. The instant disclosure does not set forth evidence ascribing unexpected results due to the claimed dimensions. See *Gardner v. TEC Systems, Inc.*, 725 F.2d 1338 (Fed. Cir. 1984), which held that the dimensional limitations failed to point out a feature which performed and operated any differently from the prior art.

Pellerin discloses the semiconductor device as claimed in claim 1, the side wall spacer (40/52) has a shaped (as seen Fig. 2) and comprises a first portion, which borders on the gate and extends substantially perpendicularly with respect to the surface of the semiconductor body, and a second portion which extends along the surface of the semiconductor body (as seen in Fig. 2D).

Pellerin does not disclose the following limitation whereas Fig. 1 of Krivokapic teaches it is known in the art to provide a side wall spacer (48 or 60) is L-shaped.

It would have been obvious to one of ordinary skill in the art at the time of the invention was made to provide the L-shape of the side wall of Krivokapic in Pellerin, order to isolate the active element.

Furthermore, the shape of the side wall spacer was a matter of choice which a person of ordinary skill in the art would have found obvious absent persuasive evidence that the particular configuration of the side wall spacer was significant. See *In re Dailey*, 357 F.2d 669, 149 USPQ 47 (CCPA 1966).

**Re. claim 13,** Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses wherein the side wall spacer (40/52) is configured to directly contact the entire surface of a side of the gate (46/50).

**Re. claim 14,** Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses semiconductor device as claimed in claim 1, wherein the side wall spacer (40/52) is configured to contact the entire surface of a side of the gate (46/50) without an intervening structure.

**Re. claim 15,** Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses an insulation layer (48) that is located below the gate (46/50), wherein the side wall spacer (40/52) is configured to directly contact the insulation layer (48).

**Re. claim 16,** Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses an insulation layer (48) that is located below the gate (46/50), wherein the gate (46) comprises a conductive layer (46) and a silicide layer (50), and wherein the side wall spacer (40/52) is configured to directly contact the insulation layer, the conductive layer and the silicide layer (as seen in Fig. 2D).

**Re. claim 17,** Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses comprising an insulation layer (48) that is located below the gate (46/50), wherein the gate comprises a metal conductive layer (pg. 4, line 14 of Pellerin), and wherein the side wall spacer (40/52) is configured to directly contact the insulation layer and the metal conductive layer (as seen in Fig. 2D).

**Re. claim 18,** Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses semiconductor device as claimed in claim 1 further comprising an insulation layer (48) that is located below the gate (46/50), wherein the gate comprises a conductive layer (46) that is made of polycrystalline silicon (pg. 4, line 14 of Pellerin), and wherein the side wall spacer (40/52) is configured to directly contact the insulation layer and the conductive layer (as seen in Fig. 2D).

**Re. claim 19,** Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses semiconductor device as claimed in claim 1, Pellerin and Krivokapic do not disclose wherein the second portion of the L-shaped side wall spacer has a thickness, measured in a direction perpendicular to the surface of the semiconductor body, of 5 to 20 nm.

It would have been obvious to one having ordinary skill in the art at the time of the invention was made to include wherein the second portion of the L-shaped side wall

spacer has a thickness, measured in a direction perpendicular to the surface of the semiconductor body, of 5 to 20 nm in the combined device, in order to optimize the performance of the device.

Furthermore, it has been held that where the general conditions of a claim are disclosed in the prior art, discovering the optimum or workable ranges involves only routine skill in the art. *In re Aller*, 105 USPQ 233.

Furthermore, it has been held in that the applicant must show that a particular range is critical, generally by showing that the claimed range achieves unexpected results relative to the prior art range. *In re Woodruff*, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990). Note that the law is replete with cases in which when the mere difference between the claimed invention and the prior art is some dimensional limitation or other variable within the claims, patentability cannot be found. The instant disclosure does not set forth evidence ascribing unexpected results due to the claimed dimensions. See *Gardner v. TEC Systems, Inc.*, 725 F.2d 1338 (Fed. Cir. 1984), which held that the dimensional limitations failed to point out a feature which performed and operated any differently from the prior art.

**Re. claim 20**, Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses the silicide region (50) contains a metal (see pg. 5, lines 39-40) which, in the silicide region formed, has a higher diffusion rate than silicon (Pellerin teaches the silicide region has the same material as claimed

invention; therefore it has higher diffusion rate than silicon, see claim 3 below for claimed material).

Pellerin and Krivokapic do not disclose wherein the second portion of the L-shaped side wall spacer has a thickness, measured in a direction perpendicular to the surface of the semiconductor body, of maximally 40 nm.

It would have been obvious to one having ordinary skill in the art at the time of the invention was made to include wherein the second portion of the L-shaped side wall spacer has a thickness, measured in a direction perpendicular to the surface of the semiconductor body, of maximally 40 nm in the combined device, in order to optimize the performance of the device.

Furthermore, it has been held that where then general conditions of a claim are disclosed in the prior art, discovering the optimum or workable ranges involves only routine skill in the art. *In re Aller*, 105 USPQ 233.

Furthermore, it has been held in that the applicant must show that a particular range is critical, generally by showing that the claimed range achieves unexpected results relative to the prior art range. *In re Woodruff*, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990). Note that the law is replete with cases in which when the mere difference between the claimed invention and the prior art is some dimensional limitation or other variable within the claims, patentability cannot be found. The instant disclosure does not set forth evidence ascribing unexpected results due to the claimed dimensions. See *Gardner v. TEC Systems, Inc.*, 725 F.2d 1338 (Fed. Cir. 1984), which

held that the dimensional limitations failed to point out a feature which performed and operated any differently from the prior art.

**Re. claim 21**, Pellerin and Krivokapic disclose discloses the semiconductor device as claimed in claim 1, Pellerin further discloses the silicide region (50) contains a metal (see pg. 5, lines 39-40) which, in the silicide region formed, has a higher diffusion rate than silicon (Pellerin teaches the silicide region has the same material as claimed invention; therefore it has higher diffusion rate than silicon, see claim 3 below for claimed material), and wherein an insulating layer (48) extends in the semiconductor body in a direction parallel to the surface of the semiconductor body (as seen in Fig. 2D).

### ***Conclusion***

**THIS ACTION IS MADE FINAL.** Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire **THREE MONTHS** from the mailing date of this action. In the event a first reply is filed within **TWO MONTHS** of the mailing date of this final action and the advisory action is not mailed until after the end of the **THREE-MONTH** shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of



the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to TRANG Q. TRAN whose telephone number is (571)270-3259. The examiner can normally be reached on Mon - Thu (9am-5pm).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Lynne A. Gurley can be reached on 571-272-1670. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/T. Q. T./  
Examiner, Art Unit 2811  
/Cuong Q Nguyen/  
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